

### IN THE CLAIMS

This listing of claims replaces all prior listings:

1. – 5. (Cancelled)

6. (Previously Presented) A method of manufacturing a micro electro-mechanical system (MEMS) resonator, comprising the steps of:

- forming a electrode on a substrate;
- forming a layer on said substrate including said electrode;
- selectively forming an opening that reaches said substrate at a portion of said layer where a support column can be formed;
- forming a beam on said layer;
- forming inside said opening the support column integrated with said beam and said substrate; and
- removing said layer.

7. – 13. (Cancelled)